

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF: Yasuji HIRAMATSU, et al.

GAU:

SERIAL NO: New Application

EXAMINER:

FILED: Herewith

FOR: CERAMIC SUBSTRATE FOR SEMICONDUCTOR FABRICATING DEVICE

**REQUEST FOR PRIORITY**

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

SIR:

☒ Full benefit of the filing date of U.S. Application Serial Number 09/926,800, filed 03/19/2002, is claimed pursuant to the provisions of 35 U.S.C. §120.

☐ Full benefit of the filing date(s) of U.S. Provisional Application(s) is claimed pursuant to the provisions of 35 U.S.C. §119(e):  
Application No. Date Filed

☒ Applicants claim any right to priority from any earlier filed applications to which they may be entitled pursuant to the provisions of 35 U.S.C. §119, as noted below.

In the matter of the above-identified application for patent, notice is hereby given that the applicants claim as priority:

**COUNTRY**

**APPLICATION NUMBER**

**MONTH/DAY/YEAR**

Japan

2000-121938

April 24, 2000

Certified copies of the corresponding Convention Application(s)

☐ are submitted herewith

☐ will be submitted prior to payment of the Final Fee

☐ were filed in prior application Serial No. filed

☒ were submitted to the International Bureau in PCT Application Number PCT/JP01/03299

Receipt of the certified copies by the International Bureau in a timely manner under PCT Rule 17.1(a) has been acknowledged as evidenced by the attached PCT/IB/304.

☐ (A) Application Serial No.(s) were filed in prior application Serial No. filed ; and

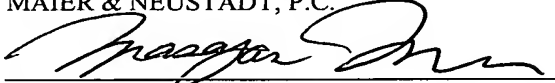
☐ (B) Application Serial No.(s)

☐ are submitted herewith

☐ will be submitted prior to payment of the Final Fee

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.



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Registration No. 47,301



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